



Application of extended MARI concept to SiC mirrors

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1. BACKGROUND

- PROGRAM OVERVIEW

1. Overview

- ❖ Collaboration between KASI and NOAO to develop SiC mirror polishing procedure and environmental testing since 2014^{1,2}
- ❖ KASI was awarded a study program to develop ‘a basic research on ultra-lightweighted off-axis aspheric optical surfaces for space application’ from National Research Foundation (NRF) of Korea for 3 years from July 2018.
- ❖ KASI is extending research field toward polishability of ultra-lightweighted mirror materials such as SiC as well as testing for off-axis aspheric mirror surfaces.
- ❖ KASI will investigate the MARI (MATERIAL Removal Indicator) concept for the polishability of lightweighted materials.

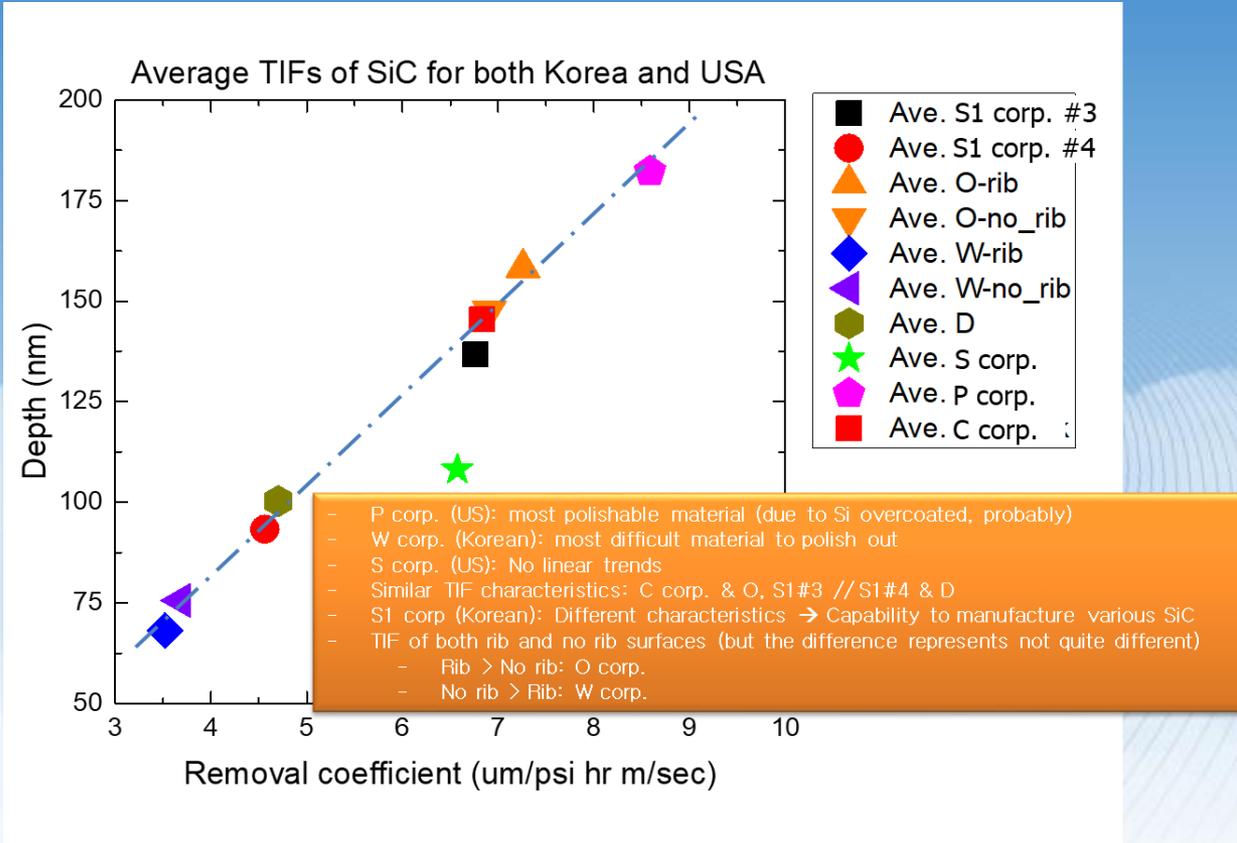
¹J.-Y. Han, et al., “Mirror polishing technology with Tool Influence Function (TIF) for SiC,” NASA Mirror Tech Days 2014.

²J.-Y. Han, et al., “International collaboration for Silicon Carbide mirror polishing and development,”
Pub. Of the Korean Astronomical Society, 30, 687~690 (2015).

1. Overview - MARI

- ❖ Used SiC materials
 - US 3 vendors and Korean 4 vendors
- ❖ Tool Influence Function(TIF) values are obtained by 27 different input conditions composed of pressure, dwell time and rotation speed.
- ❖ TIF depth and material removal coefficient is obtained.

→ MARI concept* can be used to characterize various SiC materials



*J.-Y. Han, et al., "TIF and material removal characteristics of SiC mirror materials," NASA Mirror Tech Days 2016.



1. Overview – NRF program

❖ Objectives

- To improve prediction of accuracy for deterministic polishing of lightweighted mirror materials
- To study of quantitative measurement method and of definition for an off-axis aspheric surfaces

❖ Schedule and budget

- Schedule: July 2018 ~ June 2021 (3 years)
- Budget: 350 M Won (~300,000 USD)

❖ Deliverables

- TIF experiments and analysis
- Characterization of off-axis aspheric surfaces and measurement of physical property for off-axis aspheric mirror surfaces
- All academic achievements will be encouraged to publish to journal or international conferences.

2. EXPERIMENTAL PLAN

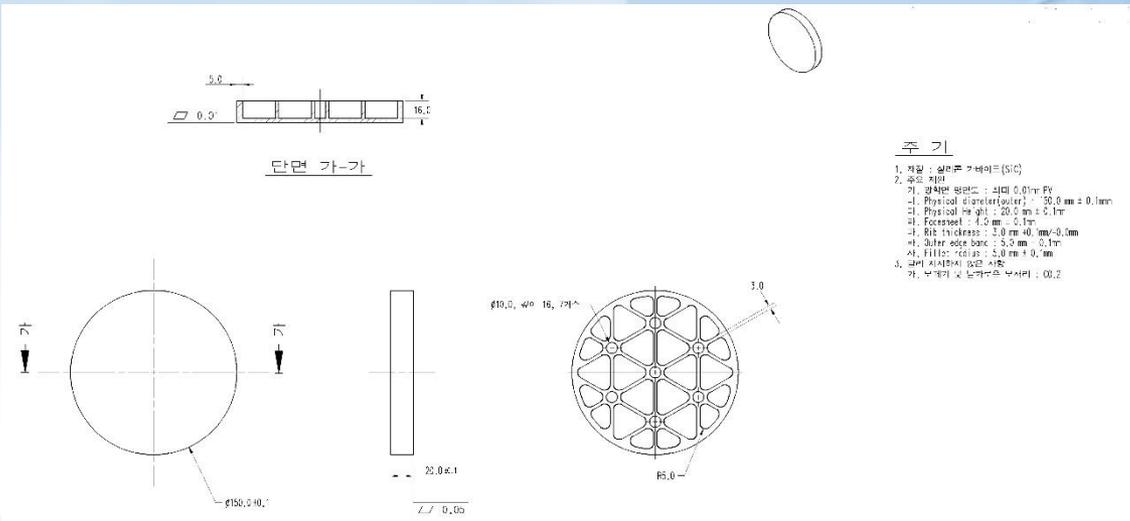
2. MARI experiment plan

❖ Materials

- SiC: RB, Sintered, Conversion, and Hybrid SiCs
- Other ultra-lightweight materials

❖ Size and drawing of Sample

- Size: 150 mm in diameter x 2ea, lightweighted
 - TIF patterns engraving: 81 TIFs (=27 input variables x 3 redundancies),
TIF on Rib and Ron-rib surfaces
- Drawing (not fixed)
 - Vendor may suggest optimized drawing incorporated with their own manufacturing process



2. MARI experiment plan

❖ Polishing head

- Orthogonal Velocity Tool (OVT)^{1,2} in KASI
- Simple configuration with two rotation axes and High repeatability of about 90%

OVT (Orthogonal Velocity Tool)

Items		Detailed items	Ranges / Spec.
Req.	TIF shape		Gaussian shape
Spec.	Wheel	Rotation speed	15~1000 rpm
		Contact width	3.8 ~ 3.9 mm
		Contact area	6.0 ~ 6.5 mm ²
	Rotational axis (Radial direction)	Rotation speed	4~60 rpm
	Load cell	Motion control item	Rotation angle Dwell time
Development		Measurement ranges	Min.: 0.1 psi Max.: 10 psi
		KASI, SphereDyne, YoonSeul	



TIF polishing head

❖ Input variables: Pressure(P), Rotation speed(V), Dwell time(T)

❖ Outcomes: TIF depth and volume

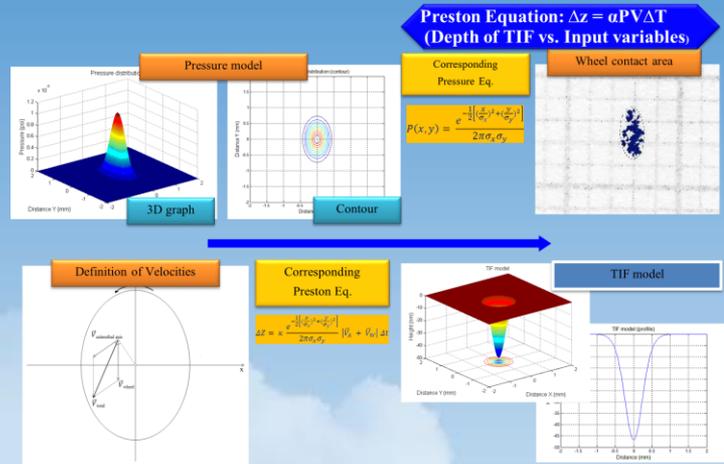
¹H.Seo, et al., “Novel Orthogonal velocity polishing tool and its material removal characteristics from CVD SiC mirror surfaces,” Opt. Express., 24, 12349 (2016).

²J.-Y. Han, et al., “Tool Influence Function (TIF) Characteristics of SiC mirrors,” NASA Mirror Tech Days 2015.

2. MARI experiment plan

❖ TIF model: Analytical and empirical model^{1,2}

- Basic relationship between input and output variables: Preston equation



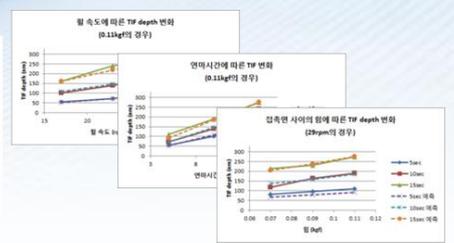
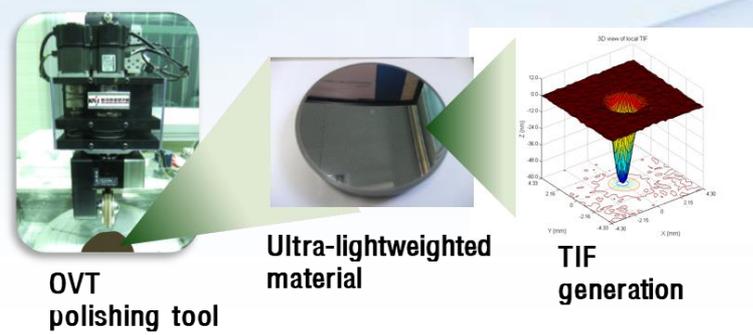
❖ Collaboration

- NOAO: Oversight for the SiC and ultra-lightweighted materials and applications
- Green Optics(GO): Polishing the mirror surfaces
- Material providers: KASI welcomes a mirror sample provider to have a novel and excellent physical property to check polishability. Please let me know if you have an interesting to check.

¹H.Seo, et al., “Novel Orthogonal velocity polishing tool and its material removal characteristics from CVD SiC mirror surfaces,” Opt. Express., 24, 12349 (2016).
²J.-Y. Han, et al., “Tool Influence Function (TIF) Characteristics of SiC mirrors,” NASA Mirror Tech Days 2015.

2. MARI experiment plan - Summary

- ❖ Materials: 150 mm in diameter
 - SiC: RB, Sintered, Conversion, and Hybrid SiCs
 - Other ultra-lightweight materials
- ❖ Polishing head: Orthogonal Velocity Tool (OVT) in KASI
- ❖ Input variables: Pressure, Dwell time, Rotation speed
- ❖ Outcomes: TIF depth and volume
- ❖ TIF model: Analytical and Empirical model
- ❖ Collaboration
 - NOAO, GO and material providers



TIF analysis
→ Apply to MARI concept

3. FABRICATION EXAMPLE OF OFF-AXIS ASPHERIC SURFACES

3. Fabrication of off-axis aspheric optical surfaces (1/2)

❖ Objectives

- i) To fabricate SiC mirror and ii) to develop a metrology to measure an off-axis aspheric surfaces

❖ Fabrication for SiC

Material: SiC
R: 850.45 mm, K: -1.147
CA: 300 mm, Central hole: 128 mm

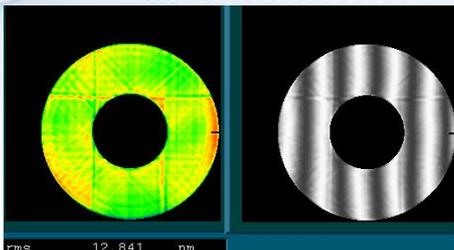


Material

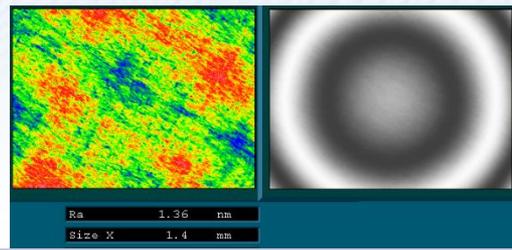


Grinding

Polishing and measurement



Surface error: 12.8 nm



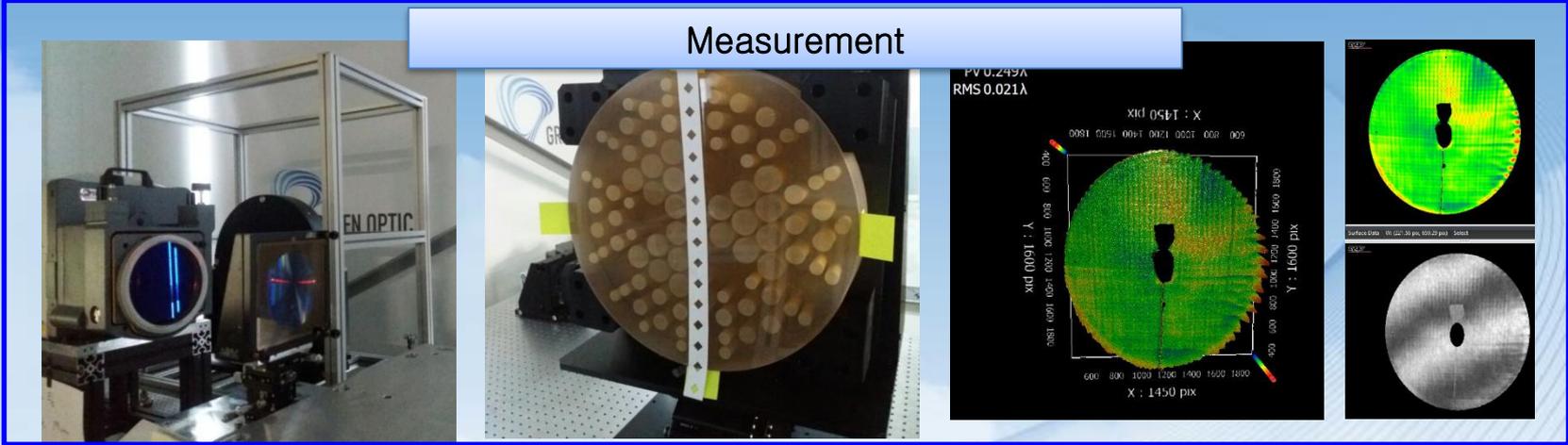
Surface roughness: 1.36 Ra

3. Fabrication of off-axis aspheric optical surfaces (2/2)

❖ Measurement of off-axis aspheric surfaces

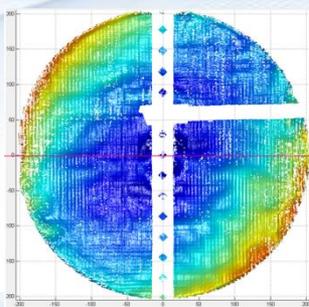
Material: Zerodur
R: 1670.106 mm, K: -1.0
CA: 400 mm, OAD: 340 mm

Measurement



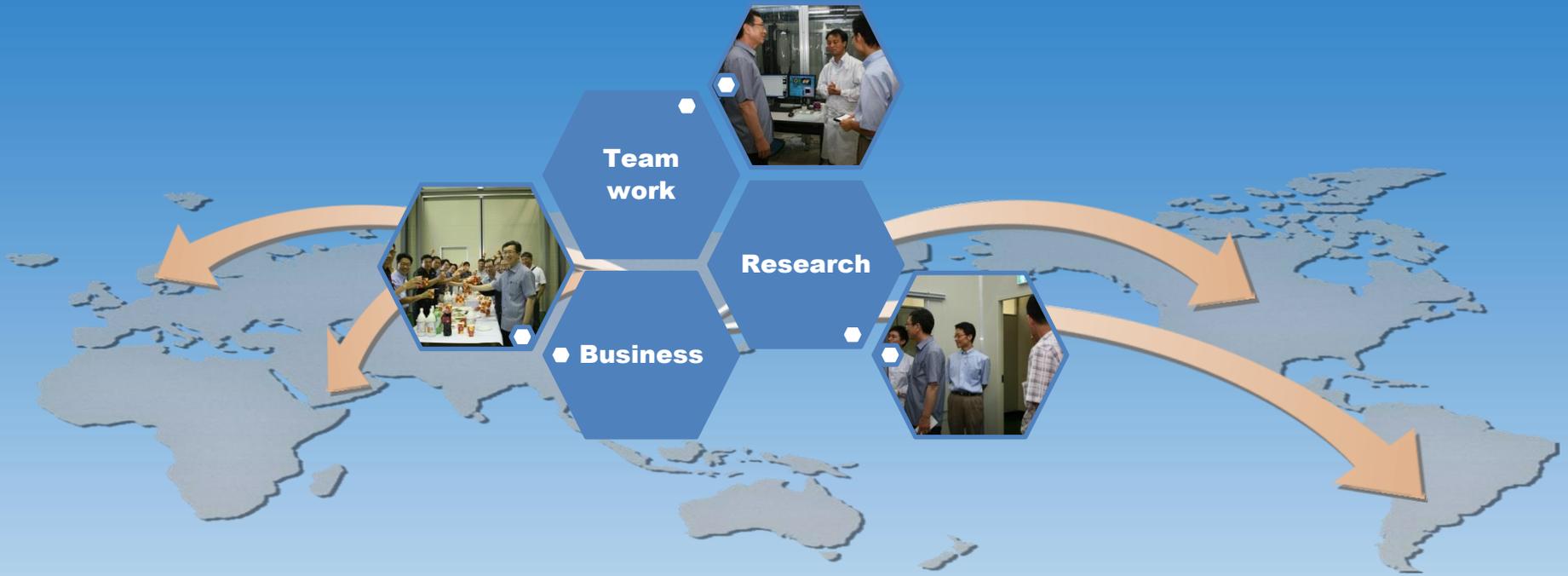
Distortion correction

Surface error: 13.3 nm



4. Conclusion

- ❖ KASI has plan to extend MARI concept for various SiC and ultra-lightweighted materials for three years with NOAO, GO, and material providers.
- ❖ In order to get TIF, KASI implemented OVT as a polishing head and TIF model.
- ❖ KASI and GO is developing deterministic fabrication and measurement processes for off-axis aspheric optical surfaces



**Thank you for
your attention**